

Vapor Phase Self-Assembly of Electrooptic Thin Films via Triple Hydrogen Bonds

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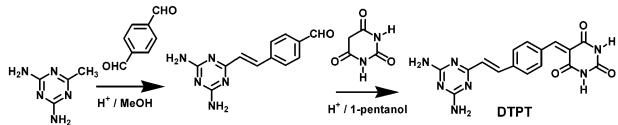
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Molecule-based electrooptic (EO) materials represent a promising direction in the quest to develop novel technologies for greatly increased optical data network speed, capacity, and bandwidth.¹ Microstructural acentricity is a key, yet synthetically daunting, challenge for such materials, with electric-field poling of chromophoric glassy polymers,² Langmuir–Blodgett (LB) film transfer,³ and layer-by-layer formation of covalent self-assembled superlattices (SASs)^{4,5} representing the principal avenues pursued to date. In addition to attractions, each approach also poses challenges ranging from the inherent thermodynamic instability of poled dipole-containing glasses,² to the modest efficiency of most layer-by-layer growth techniques,^{3–6} to the fragility of amphiphilic lattices enforced principally by van der Waals interactions.³ We report here an alternative, vapor phase approach which utilizes robust patterns of directed triple hydrogen bonds to assemble microstructurally acentric, EO-active films in an expeditious growth process.

Although directed multiple H-bonds are widely used in crystal engineering,^{7,8} few reports describe thin film deposition using H-bonding constituents.⁹ “Oblique incidence organic molecular beam deposition” produces preferentially oriented thin films¹⁰ with single H-bonds used to align pyridylbenzoic acid chromophore molecules. However, in this case, the molecular dipoles are aligned parallel to the substrate, and only in-plane directional ordering is achieved (disadvantageous for conventional thin film waveguiding devices).^{2,4} The present approach utilizes specifically designed intermolecular longitudinal triple H-bonding interactions to align chromophore molecules head-to-tail and preferentially perpendicular to the substrate, as thin solid films from the vapor phase. Out-of-plane noncentrosymmetric microstructures are thereby achieved in smooth, optically clear, thermally robust films which can be grown in a few hours. Parallel theoretical work shows that such minimal energy head-to-tail chromophore orientations also afford intermolecular cooperative effects which substantially enhance the effective molecular hyperpolarizability.¹¹ The chromophore 5-[4-{2-(4,6-diamino-[1,3,5]triazin-2-yl)-vinyl]-benzylidene}-pyrimidine-2,4,6-trione (**DTPT**) containing H-bond/electron donor and H-bond/electron acceptor modules was synthesized in two steps (Scheme 1)

Scheme 1. Synthesis of 5-[4-{2-(4,6-Diamino-[1,3,5]triazin-2-yl)-vinyl]-benzylidene}-pyrimidine-2,4,6-trione (**DTPT**)

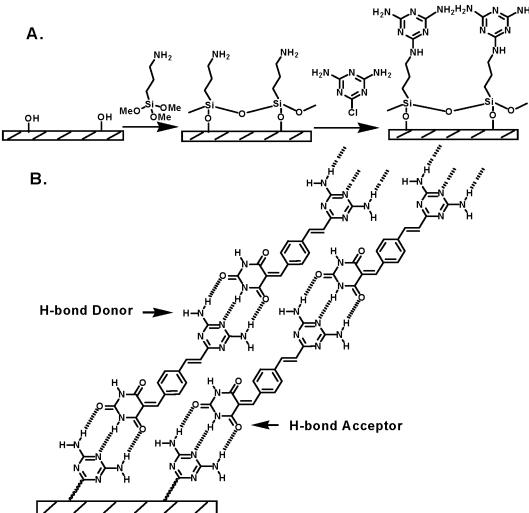


and characterized by conventional analytical/spectroscopic techniques.¹² The pyrimidine-2,4,6-trione and 4,6-diamino-1,3,5,-

triazine-2-yl moieties form longitudinally directed donor–acceptor triple H-bonds between neighboring molecules. The basic structural and thermodynamic characteristics of such linkages have been well-characterized.^{7,8}

In film growth experiments, a melamine template was first anchored to the cleaned glass or Si (100) substrate (Scheme 2, A),

Scheme 2. (A) Substrate Functionalization for **DTPT** Self-Assembly; (B) Scheme for **DTPT** Self-Assembly



and the functionalized substrates were characterized by XPS. A Denton Vacuum DV-502 deposition apparatus (10^{-5} – 10^{-6} Torr) was then used to fabricate **DTPT** films at an optimized substrate temperature of 100 °C and growth rate of 0.5–2.0 Å/s. A calibrated quartz crystal sensor was used to monitor the film growth rate and approximate thickness. The resulting films are optically transparent ($\alpha \approx 10 \text{ cm}^{-1}$ at 640–1800 nm, $\lambda_{\max} = 332 \text{ nm}$) and smooth by contact mode AFM (rms roughness = 1.7 nm over a $25 \mu\text{m}^2$ area for a $1.22 \mu\text{m}$ -thick film). Polarized transmission second harmonic generation (SHG) measurements at $\lambda_0 = 1064 \text{ nm}$ were carried out on samples placed on a computer-controlled rotation stage.⁶ Angle-dependent interference patterns for glass substrates coated on both sides (Figure 1 inset) demonstrate that identical film quality and uniformity on both sides of the substrates is achieved. The quadratic dependence of the 532 nm light output intensity ($I^{2\omega}$) on film thickness (Figure 1) further demonstrates the uniformity of the chromophore orientation and that the response is a bulk rather than interface effect. Calibrating the data (Figure 1, inset) versus quartz yields $d_{33} = 0.15 \text{ pm/V}$ and $d_{31} = 0.25 \text{ pm/V}$, values consistent with the modest computed molecular hyperpolarizability [$\beta_{\text{tot}}(\omega = 0.0 \text{ eV}) = 81 \times 10^{-30} \text{ esu}$ for a linear trimer].¹¹ Using

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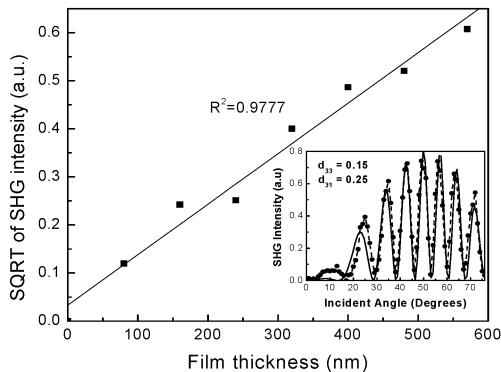


Figure 1. Square-root of the second harmonic generation response ($I^{2\omega}$) $^{1/2}$ as a function of **DTPT** film thickness. Inset: $I^{2\omega}$ as a function of the fundamental beam incident angle. The dashed line is drawn as a guide to the eye. The solid line is the fitting result.

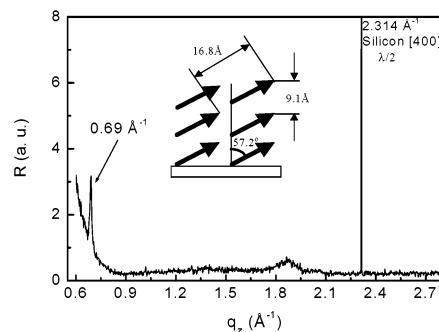


Figure 2. Specular synchrotron X-ray diffraction pattern for a thick (0.75 μ m) **DTPT** film grown on a template-functionalized Si(100) substrate. Inset: Proposed molecular alignment in film.

standard assumptions,¹³ the SHG analysis yields an average chromophore tilt angle of $\sim 56.7^\circ$ with respect to the substrate normal.

Synchrotron X-ray diffraction (XRD) techniques¹⁴ were employed to probe film microstructural regularity. The data reveal a specular feature at 0.69\AA^{-1} , which corresponds to a repeat distance of 9.1\AA (Figure 2). DFT-level molecular modeling¹¹ shows that the repeat distance between **DTPT** molecules in a H-bonded chain is $\sim 16.8 \text{\AA}$, which, combined with the XRD data, yields a molecular tilt angle from the substrate normal of $\sim 57^\circ$ in the films (Figure 2, inset). This result is in good agreement with the tilt angle derived from SHG data (vide supra) and shows that out-of-plane ordering of chromophore molecules has been achieved.

In summary, the donor–acceptor π electron chromophore **DTPT** was designed and synthesized. Triple H-bonding interactions direct self-assembled chromophore alignment in the desired molecular head-to-tail direction using a straightforward vapor phase deposition process. Angle-dependent SHG interference patterns for glass substrates coated on both sides and the quadratic dependence of the 2ω light output intensity on **DTPT** film thickness demonstrate high, uniform film quality and polarity. XRD also demonstrates long-range microstructural order and yields a molecular tilt angle in good agreement with polarized SHG data, demonstrating out-of-plane ordering of chromophore alignment. Future work will explore the scope of this growth process with second-generation chromophores.

Acknowledgment. The authors thank DARPA/ONR (SP01-P7001R-A1/N00014-00-C) and the NSF MRSEC program (DMR 0076077) for support of this research. XRD measurements were

performed at DOE-supported Beam Line X23B of the National Synchrotron Light Source. We thank Dr. S. Keinan, Prof. M. Ratner (Northwestern University), and Dr. R. Taylor (Lockheed Martin Missiles & Space) for helpful discussions.

Supporting Information Available: Details of **DTPT** synthesis, film growth, and characterization (PDF). This material is available free of charge via the Internet at <http://pubs.acs.org>.

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JA03716A